



**PATENT APPLICATION**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re the Application of:

Confirmation No.: 2221

Myounggoo LEE et al.

Group Art Unit: 1753

Application No.: 10/658,460

Examiner: R.G. McDonald

Filed: September 10, 2003

Attorney Docket No.: 029567-00004

For: **BIAS SPUTTERING FILM FORMING PROCESS AND BIAS SPUTTERING FILM FORMING APPARATUS**

**AMENDMENT UNDER 37 C.F.R. § 1.116**

**MAIL STOP AF**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

July 2, 2007

Sir:

In reply to the February 5, 2007 Office Action, the period for response being extended to July 5, 2007, by the attached Petition for Extension of Time please consider the following:

Amendments to the claims, as reflected in the listing of claims, begin on page 2;

and

Remarks, begin on page 5.